

SCANNING PROBE MICROSCOPE (SPM) FACILITY



MODEL: NT-MDT Solver P47-PRO

INSTALLATION PLACE: Surface characterization Laboratory (room No18 new building), Department of Microelectronics

DESCRIPTION: The Solver P47-PRO is a universal SPM tool for studying various types of samples in ambient conditions or in a gas chamber. It uses the scanning-by-sample scheme which provides the highest possible resolution (up to atomic) in the class at the expense of small scanning area.

SPECIFICATIONS

1. Sample Size
 - a. Standard configuration: 15mm by 10mm
 - b. Special Holder (available only in standard AFM mode): 20mm by 20mm
2. Two available scanners
 - a. 5 μm x 5 μm x 1.5 μm ($\pm 10\%$) open-loop scanner; min. scanning step of 0.0005 nm
 - b. 10 μm x 10 μm x 2 μm ($\pm 10\%$) open-loop scanner; min. scanning step of 0.0011 nm
3. Three available SPM Heads
 - a. Universal AFM Head
 - b. STM Head (standard preamplifier): 30 pA – 50 nA, RMS noise 4 pA
 - c. STM Head (low current preamplifier): 10 pA – 5 nA, RMS noise 1.5 pA
4. Available Operating Modes:
 - a. Scanning Tunneling Microscopy (STM)
 - b. Scanning Tunneling Spectroscopy (STS)
 - c. Atomic Force Microscopy (AFM) including:
 - i. Standard contact, semi-contact and non-contact AFM
 - ii. Force Modulation Mode
 - iii. Lateral Force Microscopy (LFM)
 - iv. Spreading Resistance Imaging (SRI)
 - v. Phase Imaging
 - vi. Many-Pass Techniques, such as Electrostatic Force Microscopy (EFM) and Magnetic Force Microscopy (MFM)
 - d. Atomic Force Spectroscopy
 - e. AFM (Force) and STM (Current) Lithography

APPLICATIONS

1. Structural and Electrical Surface Characterization of Various Materials
2. Local structural and electrical characterization of electronic devices
3. Nanotribology
4. Small-Scale Nanolithography

CERTIFICATION/ACCREDITATION

The facility is not certified or accredited.

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